PATENT

Attorney Docket No. 008401 08 RW Ref. No. APM/004-03-8

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

re Application of:

Kenneth COLLINS, et al.

Group Art Unit: Unknown

Entitled: PLASMA IMMERSION ION
IMPLANTATION SYSTEM INCLUDING A
CAPACITIVELY COULED PLASMA SOURCE
HAVING LOW DISSOCIATION AND LOW

MINIMUM PLASMA VOLTAGE

Examiner: Unknown

Serial No.: 10/646,526

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Filing Date: August 22, 2003

## PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Prior to taking action in this case, please amend the above-identified patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 4 of this paper.